

書類名

図面

図1

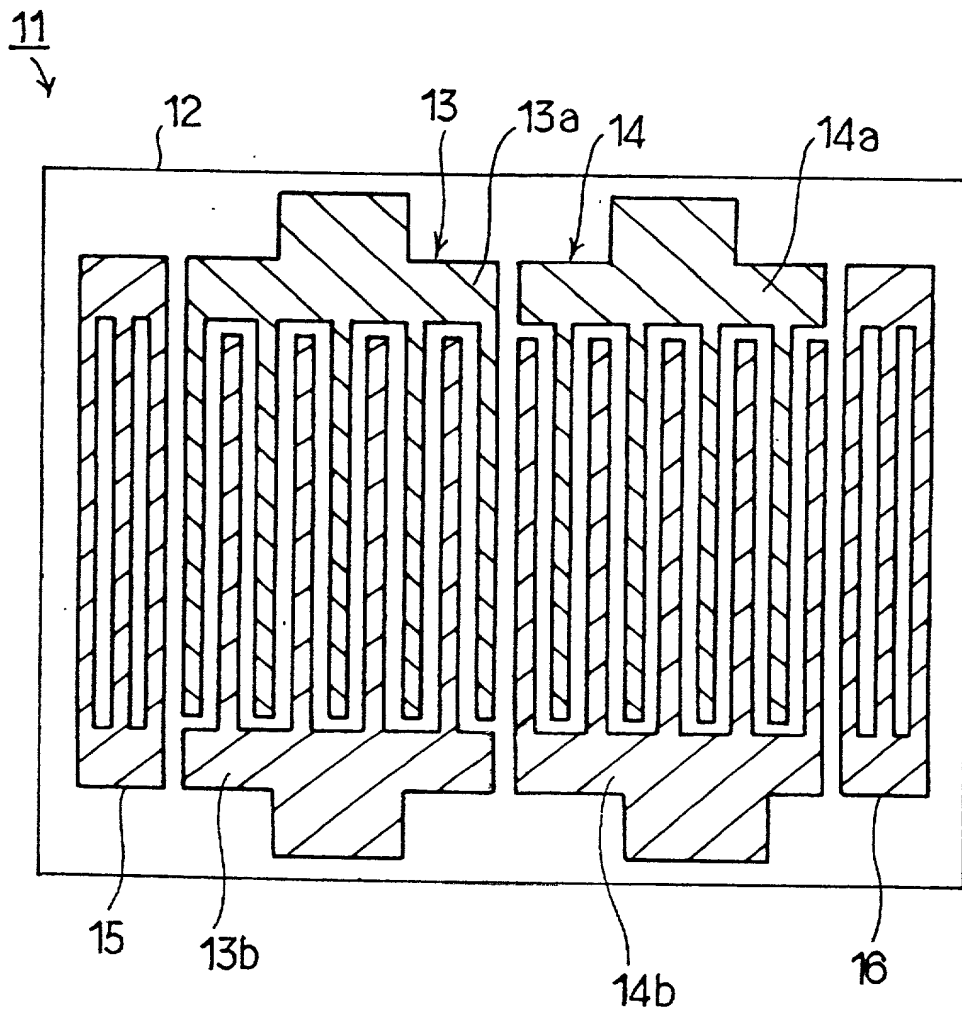
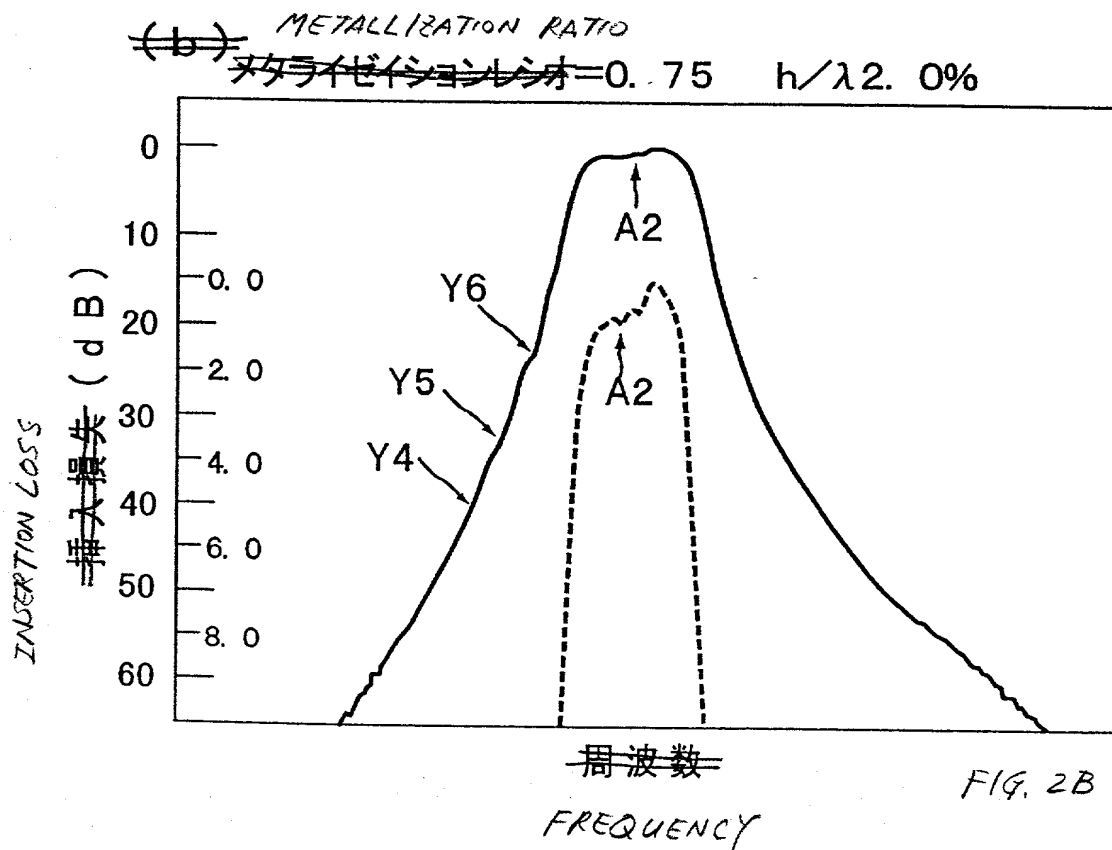
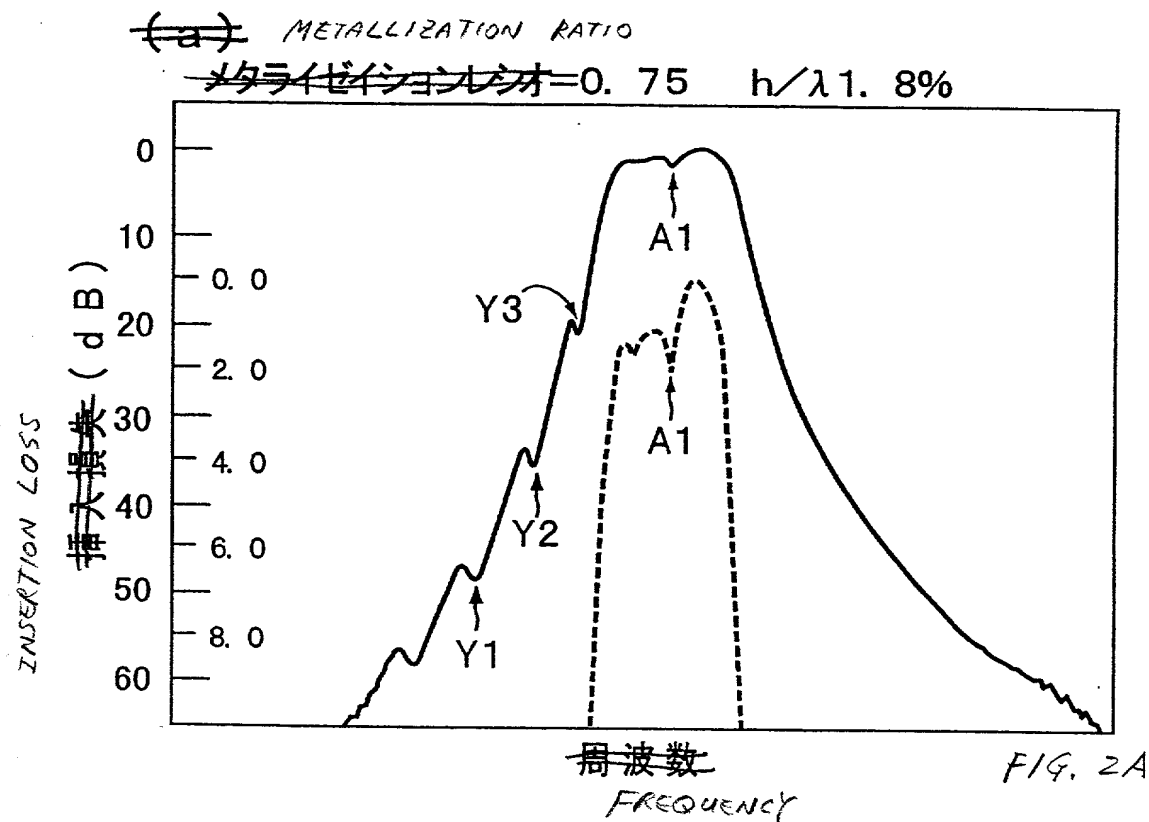


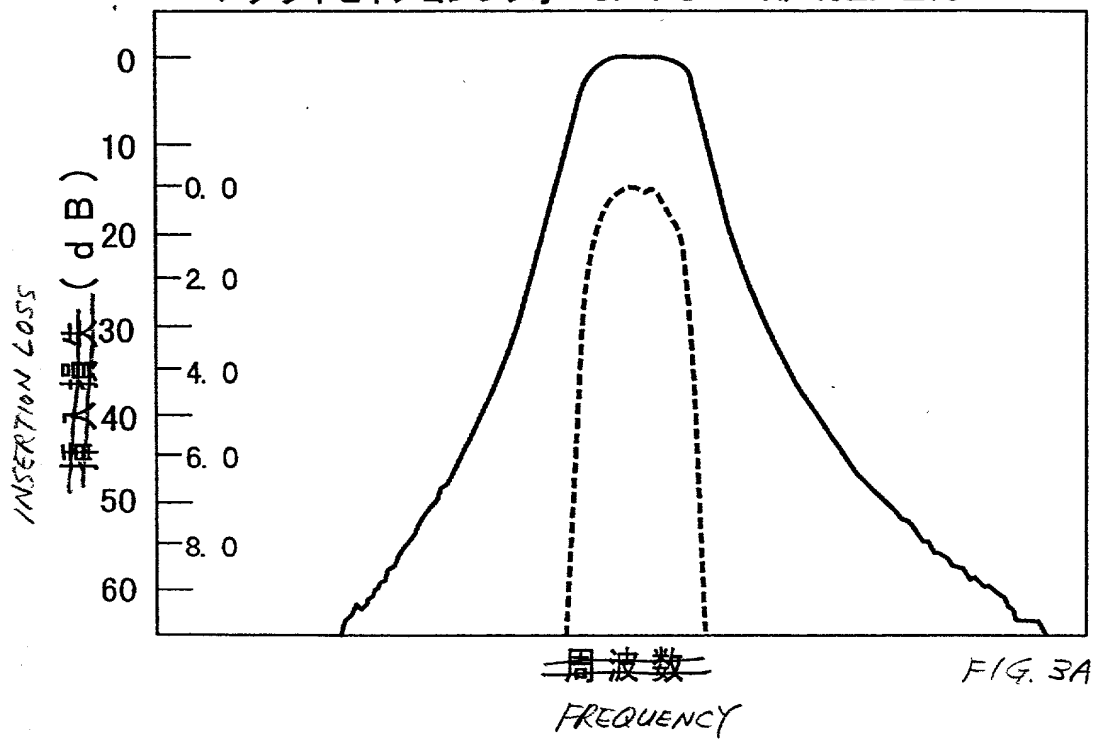
FIG. 1

~~図2~~

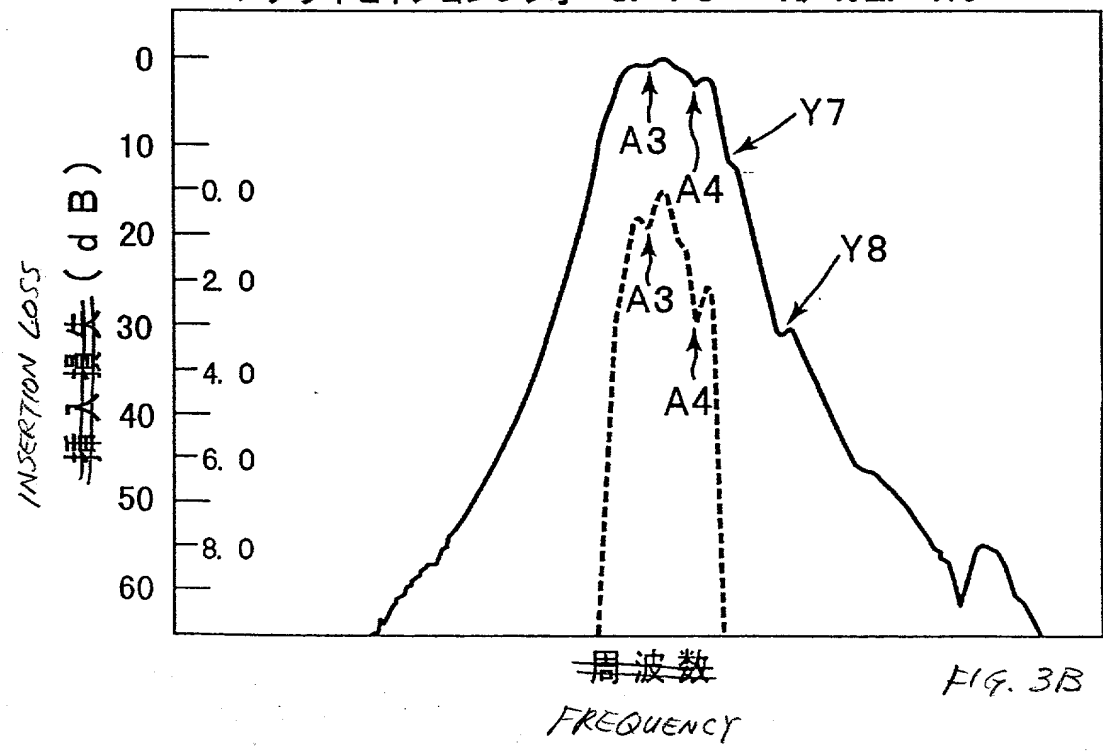


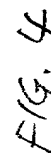
~~(図3)~~

~~(a)~~ METALLIZATION RATIO
~~メタライゼーションレシオ~~ = 0.75 $h/\lambda 2.2\%$



~~(b)~~ METALLIZATION RATIO
~~メタライゼーションレシオ~~ = 0.75 $h/\lambda 2.4\%$



$$\text{Ia/水晶の異方性指数} \quad \alpha_{\text{Ia}}/\alpha_{\text{水晶}} = 0.75$$


REMOVAL OF TRANSVERSE MODE

102260 FEB49660

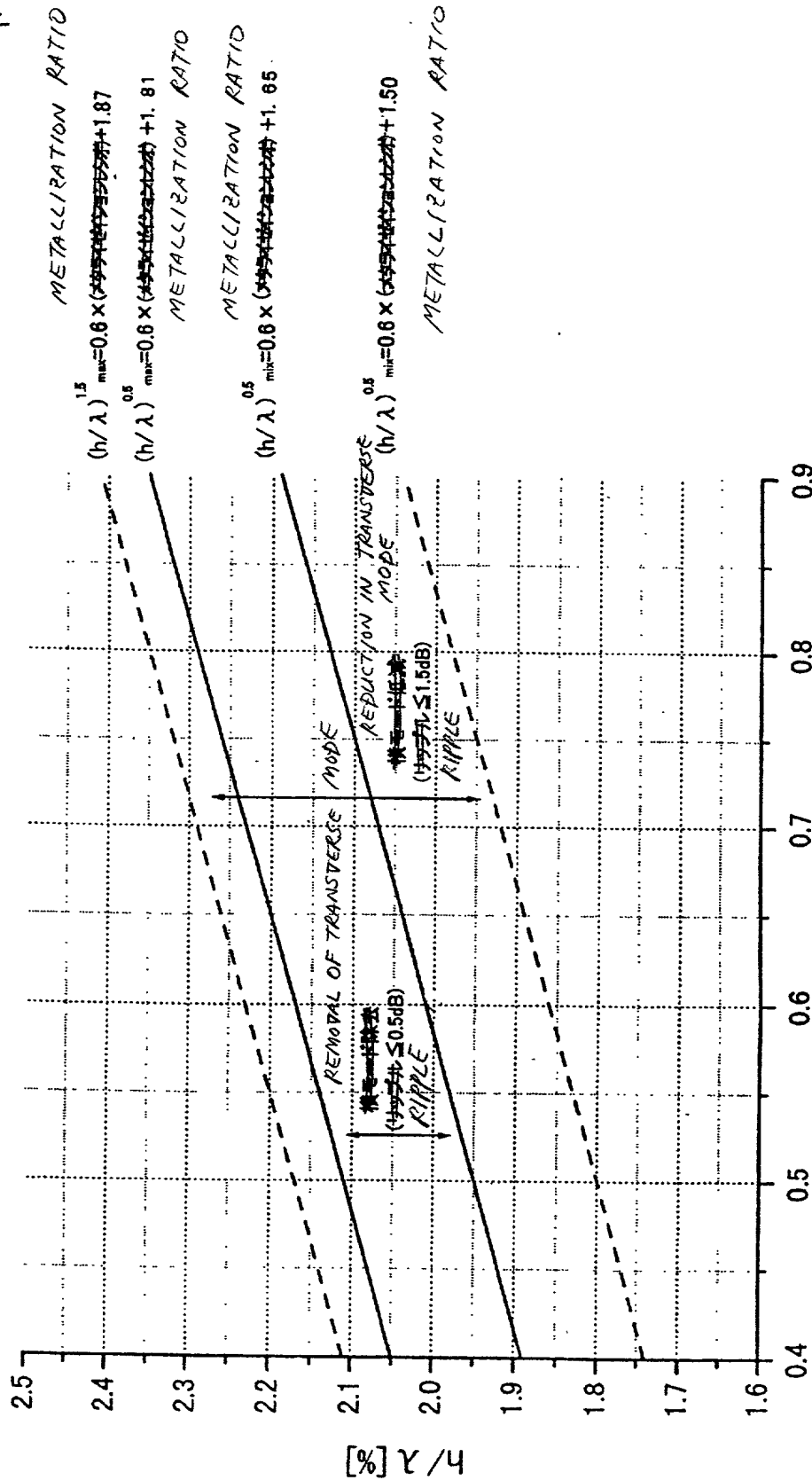
RANGE WHERE RIPPLE CAUSED BY TRANSVERSE-MODE WAVE CAN BE REDUCED

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〔図5〕

横モードによるリップルの低減可能な範囲

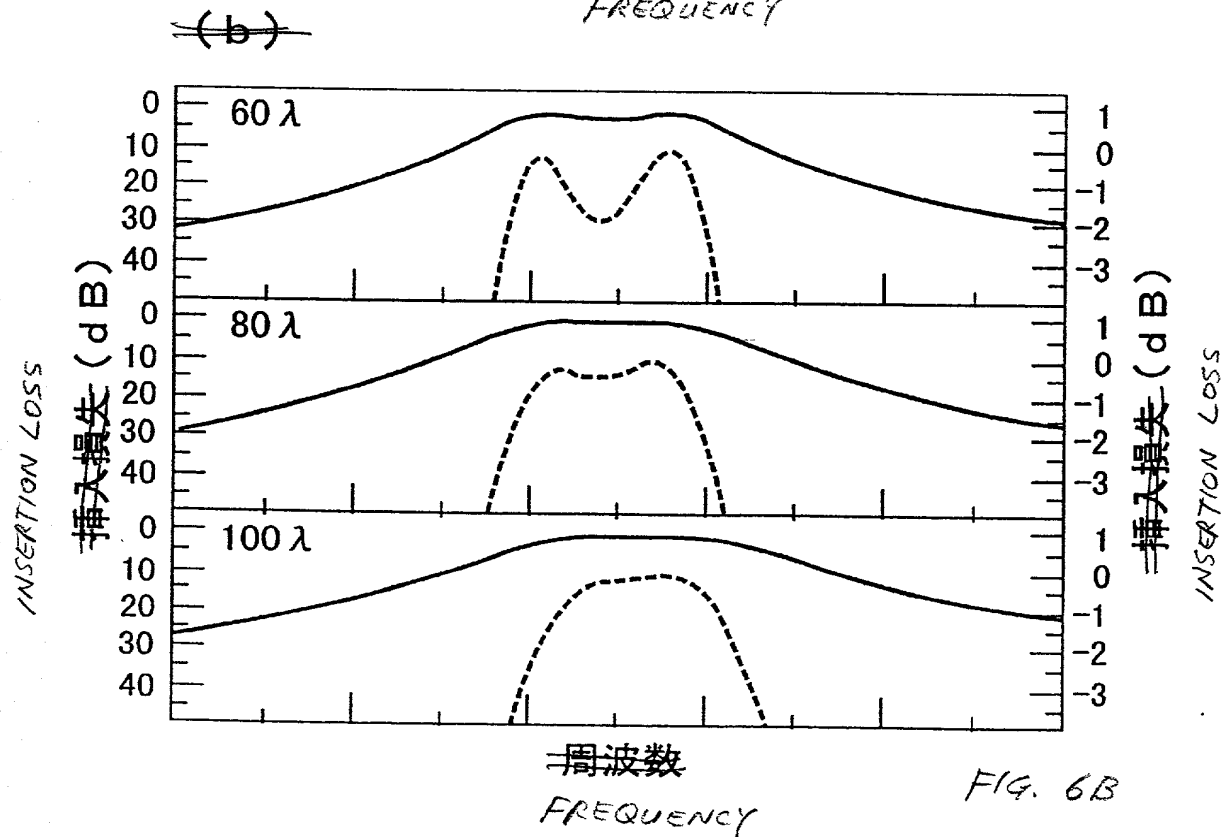
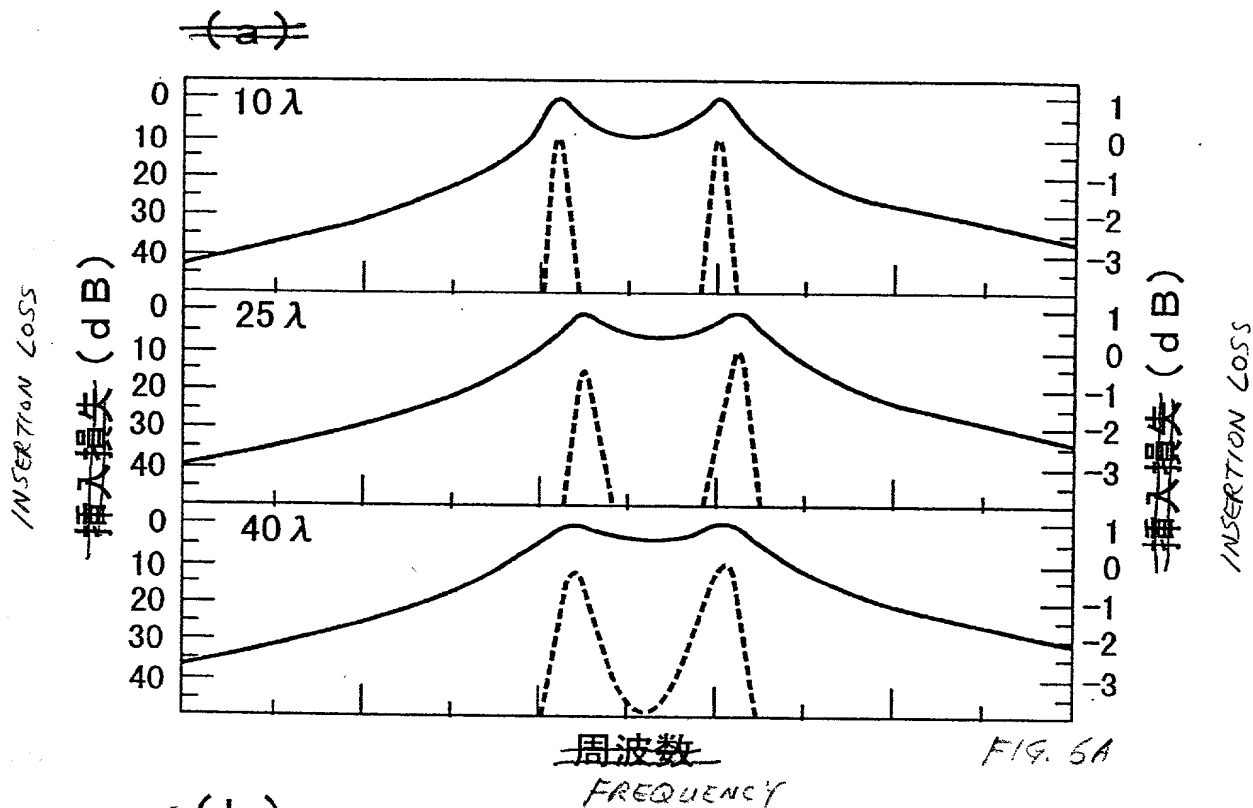


リップル低減可能な範囲

METALLIZATION RATIO

FIG. 5

~~図6~~



~~図7~~

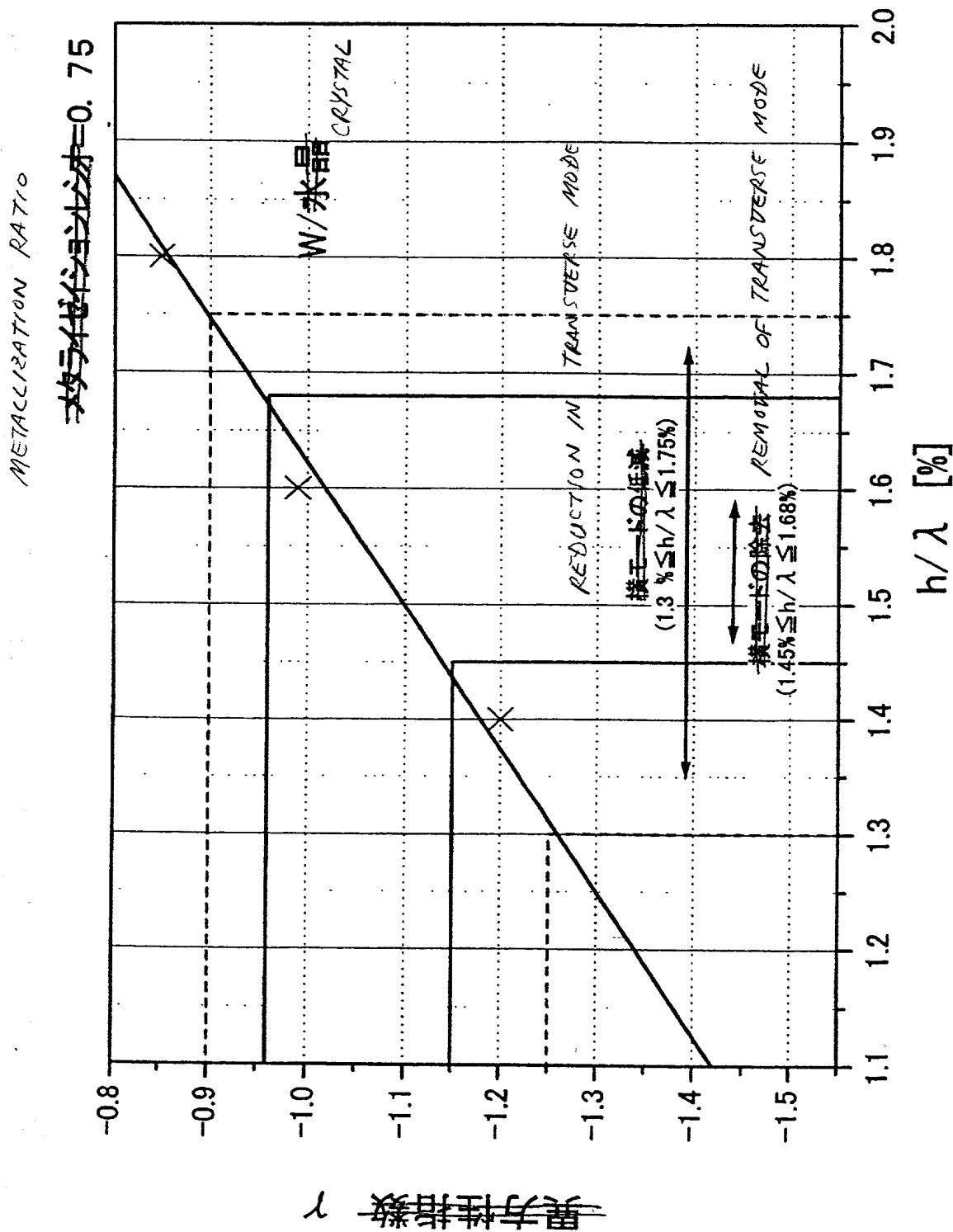


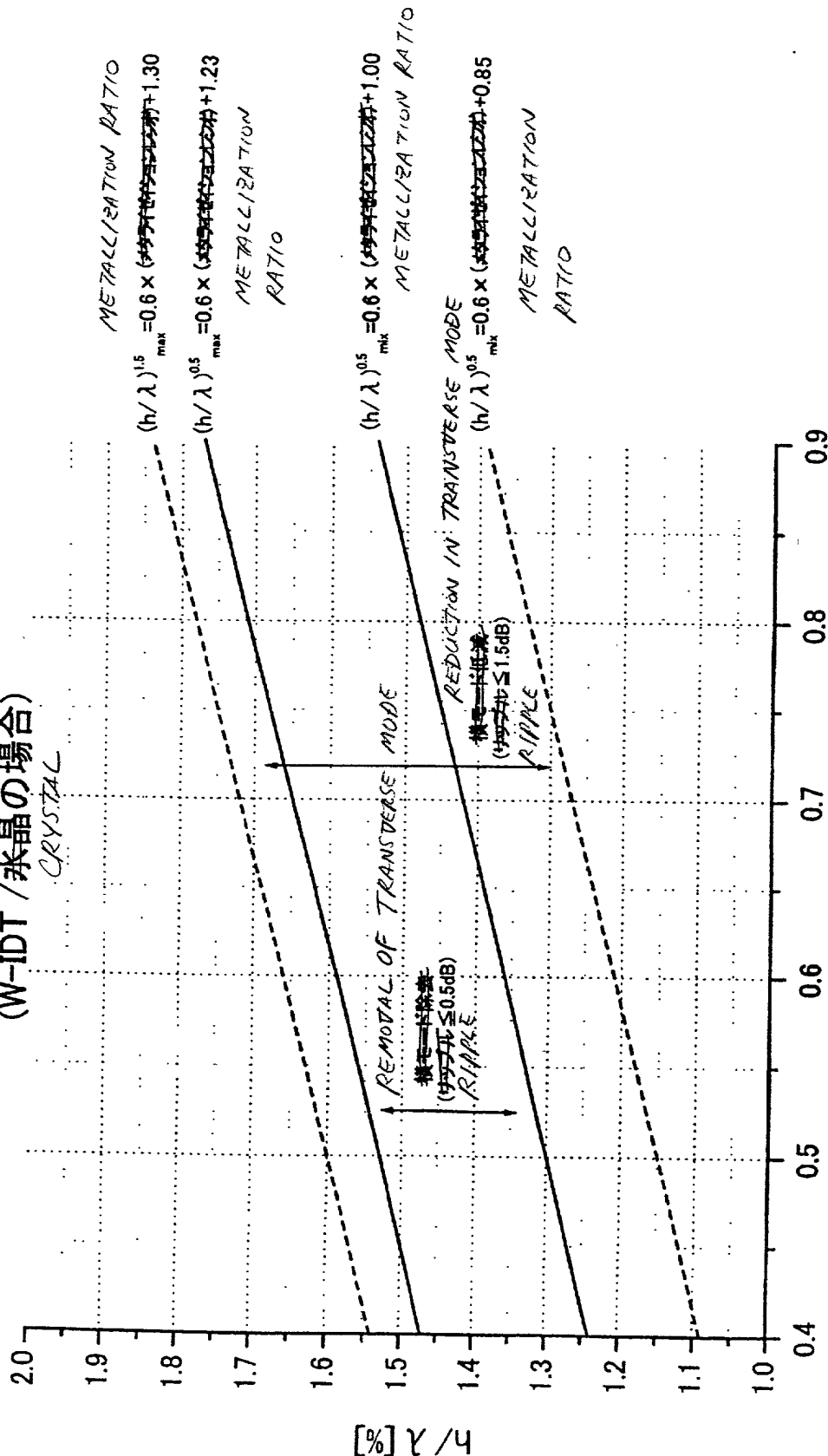
FIG. 7

RANGE WHERE RIPPLE CAUSED BY TRANSVERSE-MODE WAVE
CAN BE REDUCED

横モードによるリップルの低減可能な範囲

(W-IDT / 水晶の場合)

CRYSTAL



リップル低減

METALLIZATION RATIO

FIG. 8

〔図9〕

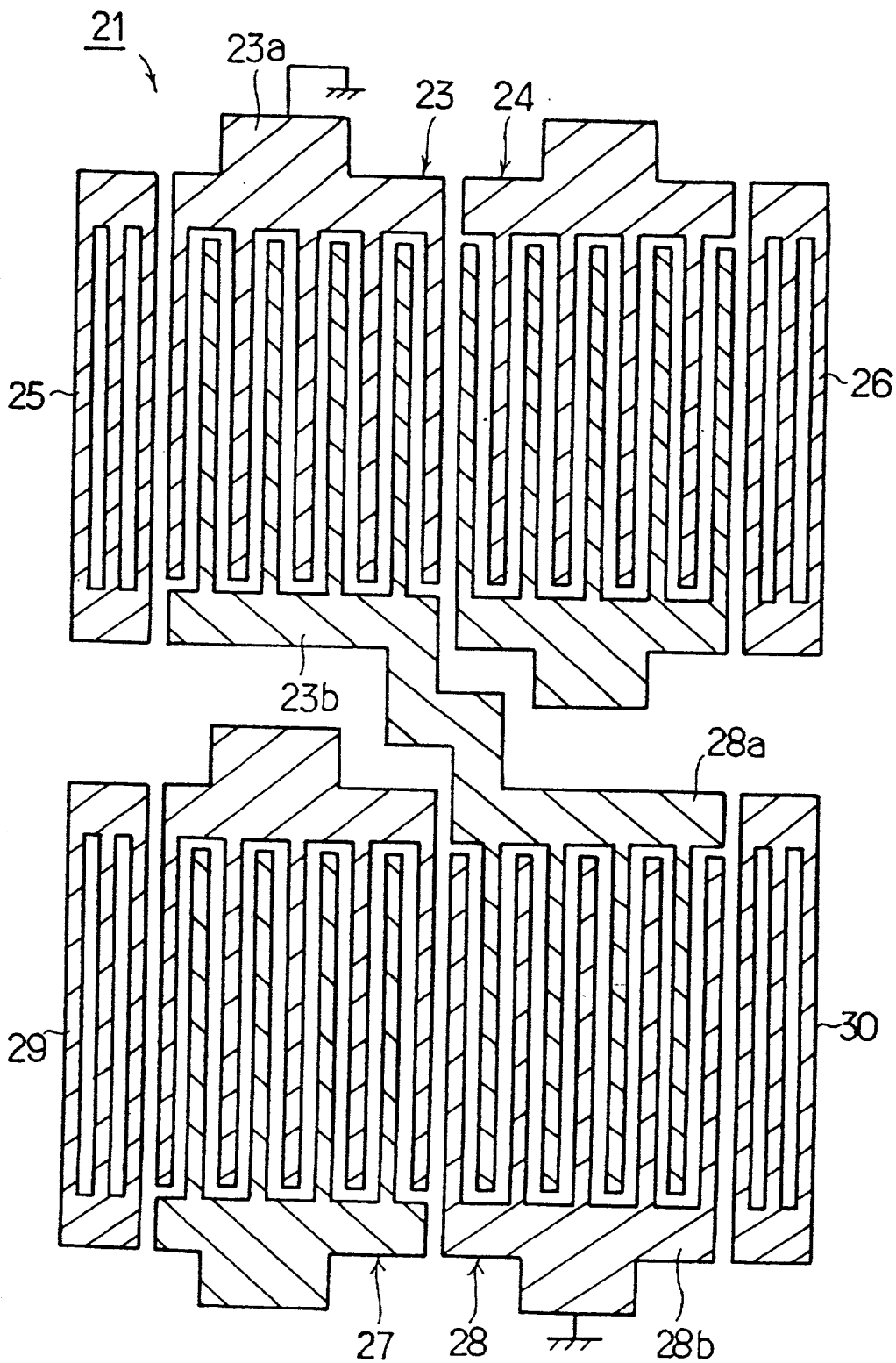


FIG. 9

~~【図10】~~

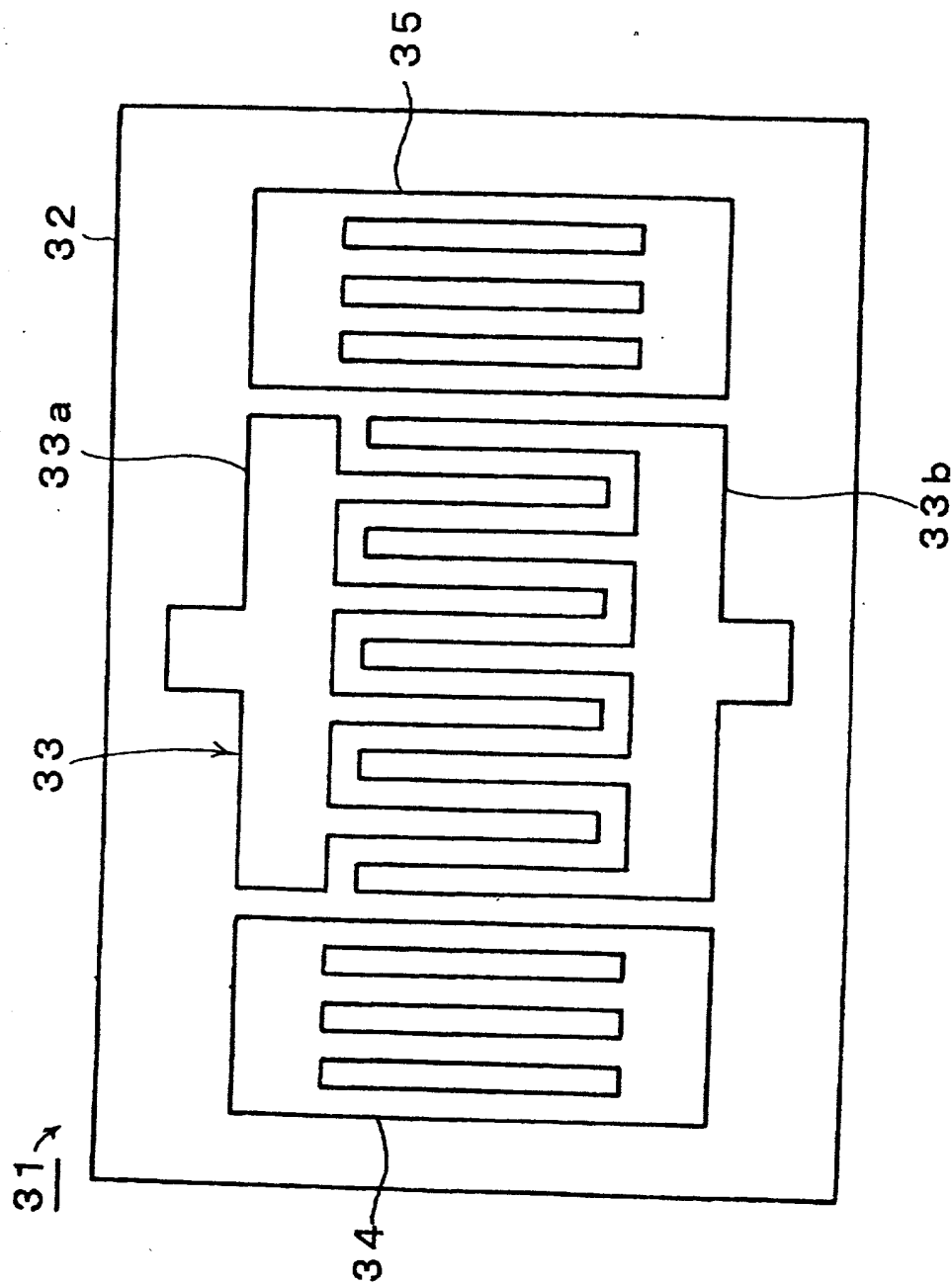


Fig. 10

~~【図11】~~

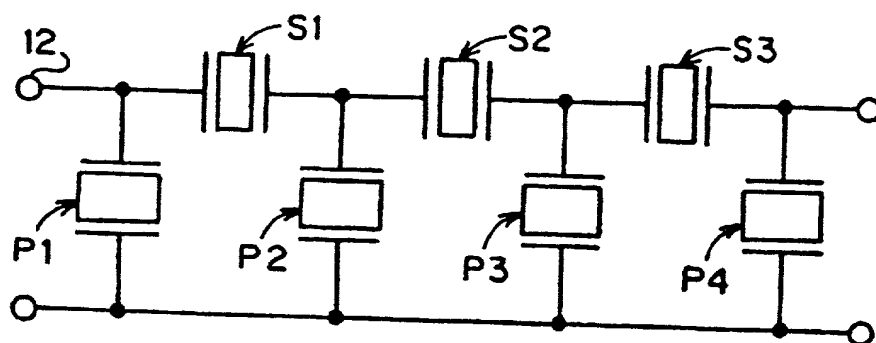


FIG. 11

~~【図12】~~

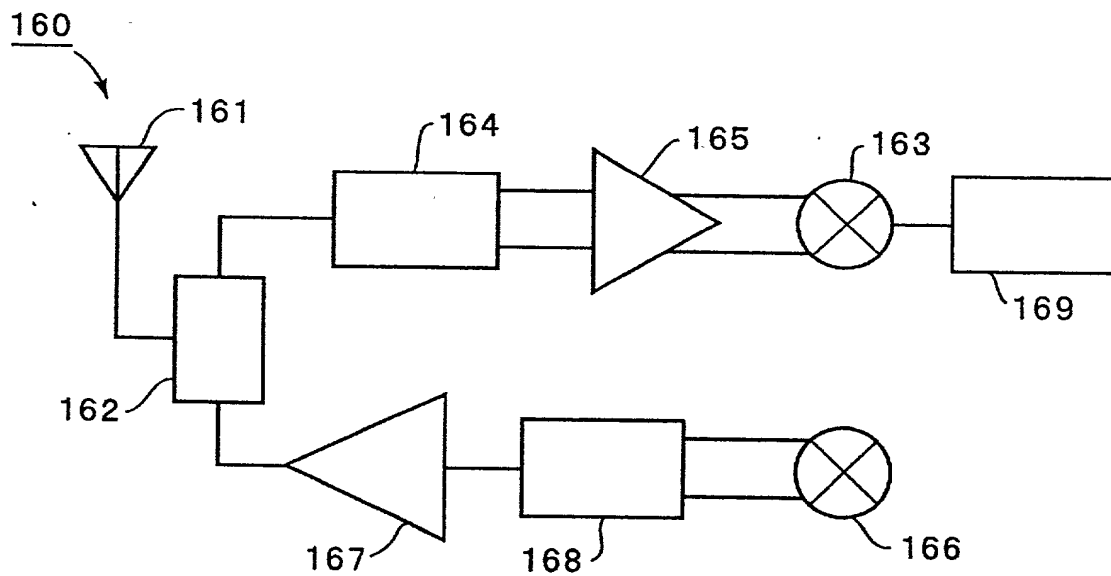


FIG. 12

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【図13】

METALLIZATION RATIO

~~メタライゼーション~~ = 0.75 h/λ 50%

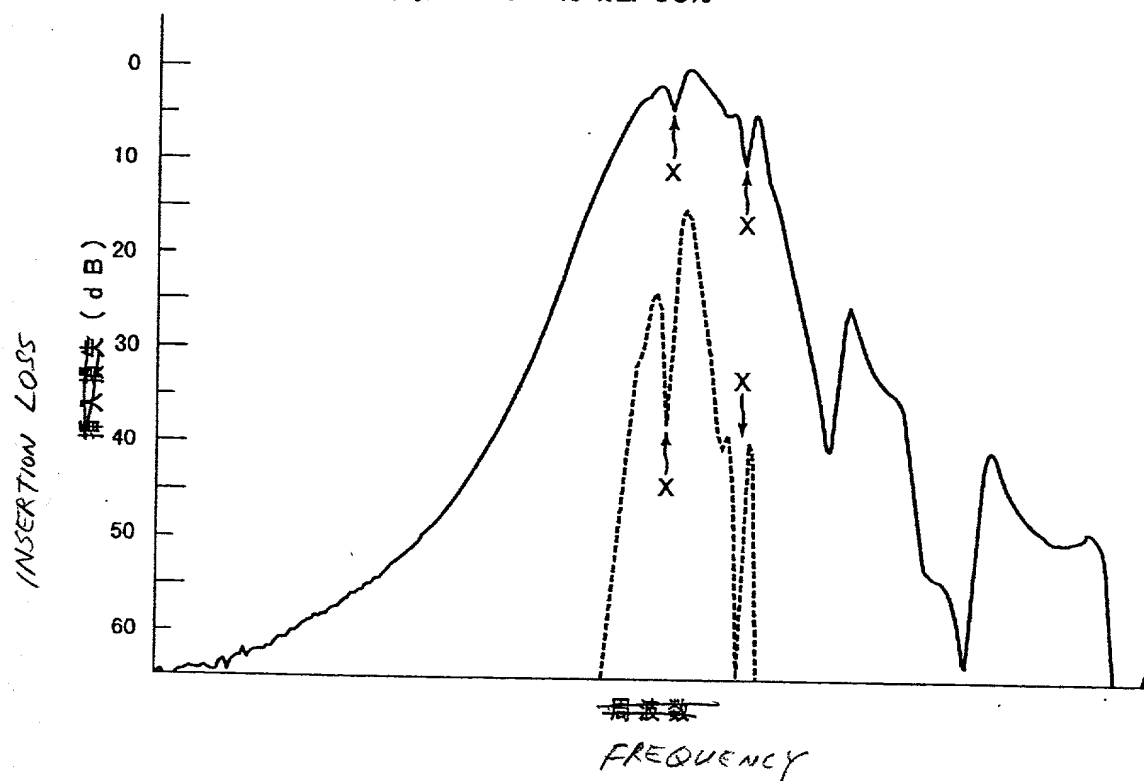


FIG. 13